

CENTER FOR NANOSCALE MATERIALS SCIENTIFIC CONTACTS

Nanofabrication and Devices

Anirudha Sumant (Group Leader).....sumant@anl.gov
superlubricity, diamond-based NEMS, CNT, graphene
wear/friction measurements

David Czaplewski.....dczaplewski@anl.gov
MEMS/NEMS, electron beam lithography, CVD

Alan Dibos.....adibos@anl.gov
nanophotonics

Ralu Divan.....divan@anl.gov
electron beam lithography, nanogels, MEMS/NEMS

Xu Han.....xu.han@anl.gov
high-frequency piezo-optomechanical spectroscopy, CVD,
ultralow temperature/strong magnetic field measurement,
FIB/SEM dual beam imaging and patterning

C. Suzanne Miller.....csmiller@anl.gov
XeF2, evaporation, RTP, dicing saw

Fubo Rao.....
clean room manager

Liliana Stan.....lstan@anl.gov
ALD, PVD, sputtering, evaporation

MAJOR TOOLS

- JEOL 8100FS, 100kV electron beam lithography
- Raith 150, 30kV electron beam lithography
- FEI Nova 600 NanoLab DualBeam FIB/SEM
- Karl Suss MA6 Optical mass aligner
- ASML PAS 5000 wafer stepper
- Direct write optical lithography
- Interferometric lithography
- Xactix XeF2 etcher
- BlueFors LD400 10mK Dilution Refrigerator System
- AMI 5-1-1Telsa Vector Magnet
- Wet chemistry & metrology
- Bruker FastScan AFM
- Deposition (Temescal ebeam evaporators, AJAs, atomic layer deposition (ALD), etc.)
- Lambda microwave plasma CVD nanocrystalline diamond
- Thermal/PECVD for CNT/graphene synthesis
- Tribometer for friction and wear measurements
- Sonotek Ultrasonic Spray Coating System
- Piezo-Optomechanical Spectrometer (POMS)

Quantum and Energy Materials

Nathan Guisinger (Group Leader).....nguisinger@anl.gov
UHV STM, AFM, 2-D materials, STS, cryo-STM

Jeffrey Guest.....jrguest@anl.gov
STM, laser spectroscopy, ambient AFM, EPR

Saw Wai Hla.....shla@anl.gov
LT-STM, SP-STM, AFM, SX-STM

Xiao-Min Lin.....xmlin@anl.gov
synthesis of nanocrystals, TGA/DSC, rotating disk electrode,
rheometry at Sector 8 of APS, glovebox

John Pearson.....pearson@anl.gov
XRD, magnetometry

Dan Rosenmann.....rosenmann@anl.gov
evaporation, deposition, sputtering

Nozomi Shirato.....nshirato@anl.gov
X-ray scanning tunneling microscopy, XRD

MAJOR TOOLS

- UHV SPM (AFM/STM) (Omicron)
- VT-AFM (Omicron XA) with optical access
- Createc LT-STM
- Cryo-STM w/magnetic field
- Scanning probe microscope, AFM (Veeco)
- Kurt Lesker electron beam evaporator and sputtering, deposition
- Agilent ICP-OES
- FT-IR w/ Hyperion Microscope
- Magnetometry (QD PPMS & MPMS)
- TGA/DSC
- Luminescence/UV-vis-NIR
- X-ray diffractometer (Bruker D2 & D8)
- Integrated glovebox system
- RheoXPCS/SAXS at Sector 8 of APS

CONTACT

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Theory and Modeling

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nanoscale oxide energy materials, machine learning

Henry Chan hchan@anl.gov
multi-scale modeling, soft materials, AI/ML for imaging and inverse design, scientific software development

Maria Chan mchan@anl.gov
photovoltaics, photocatalysts, thermoelectrics, batteries, informatics, atomistic modeling integration w/expt

Pierre Darancet pdarancet@anl.gov
charge and energy transport, optoelectronics; exciton dynamics

Stephen Gray gray@anl.gov
nanophotonics, electrodynamic

Michael Sternberg sternberg@anl.gov
software development

Nanophotonics and Biofunctional Structures

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transient absorption/emission spectroscopy, solar energy

Benjamin Diroll bdiroll@anl.gov
synthesis, time-resolved spectroscopy

Chris Fry hfry@anl.gov
synthesis, peptide synthesis, HPLC, CD, EPR

David Gosztola gosztola@anl.gov
lasers, Raman microscopy

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single molecule/particle spectroscopy

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bio(in)organic, biological chemistry, synthetic biology, GC/MS

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2-D and 3-D nanoparticle assembly, SEM

Jie Xu xuj@anl.gov
modular robotic workflow for synthesis and processing, polymer processing, wearable electronic devices

Electron and X-ray Microscopy

Martin Holt (Group Leader) mvholt@anl.gov
X-ray diffraction, ptychography and fluorescence

Electron Microscopy

Tom Gage tgage@anl.gov
Ultrafast electron microscopy (UEM)

Rachel Koritala koritala@anl.gov
SEM/TEM trainer

Haihua Liu haihua.liu@anl.gov
UEM, TEM, STEM, EELS, SAED

Yuzi Liu yuziliu@anl.gov
analytical TEM, in situ TEM

Jianguo Wen jwen@anl.gov
ACAT, TEM, batteries, PV

Synchrotron X-ray Microscopy

Tao Zhou tzhou@anl.gov
X-ray diffraction

MAJOR TOOLS

- Nanoscience Computational Facility 30 TFlop cluster for:
 - Density-functional-based tight-binding
 - Time-domain nanophotonics simulation
 - MPI-based parallel versions of nanophotonics and tight-binding codes
- GPAW; real space, grid-based DFT-PAW
- Access to Argonne computer facilities
- Support for experimental projects
- Support for theoretical projects
- (DFTB) electronic structure package
- BLAST
- FANTASTX

MAJOR TOOLS

- Ultrafast transient absorption spectroscopy
- Confocal Raman microscope, Renishaw
- VIS/NIR microscopy
- Time-resolved emission spectroscopy
- Time-correlated single photon counting
- UV-to-TH₃ ultrafast spectroscopy
- Single photon microscope for optics (SNSPD)
- Fluorescence spectroscopy
- Field-emission SEM (JEOL JSM7500F)
- Electron paramagnetic resonance (Bruker)
- Peptide synthesizer
- Adiabatic demagnetization refrigerator (ADR)
- Functionalization, electro/photochemical
- HPLC, GCMS
- Laser Scanning Confocal Microscope (Zeiss)
- Post-self-assembly processing
- ZetaSizer Nano, Malvern
- Solar simulator, QEMS (Oriol)
- FTIR (Thermo-Nicolet)
- Synthesis & surface modification of nanoparticles
- Magneto-Electrical-Optical Spectrometer (MEOS)
- Microfluidic Droplet Generation and Imaging

MAJOR TOOLS

Electron Microscopy

- ACAT: Argonne Chromatic Aberration-corrected TEM
- UEM: Ultrafast Electron Microscopy
- FEI Talos F200X TEM/STEM
- FEI Tecnai F20ST TEM/STEM
- Field-emission TEM (JEOL 2100F)
- Zeiss 1540XB FIB-SEM
- Zeiss NVision FIB-SEM
- Hitachi S-4700-II high-vacuum SEM
- FEI Quanta 400F environmental and variable-pressure SEM

X-ray Microscopy

- Hard X-ray nanoprobe beamline, Sector 26 of APS
- Scanning nanodiffraction and ptychography
- Chemical and structural nanoimaging
- Heating/cooling specimen stage
- 20-30 nm resolution, 6-12 keV
- In situ/in operando experiments